

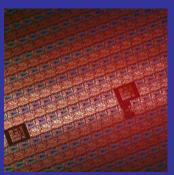
#### Accelerating the next technology revolution

#### Closing Remarks

iEUVi Mask TWG September 30, 2012, Brussels, Belgium



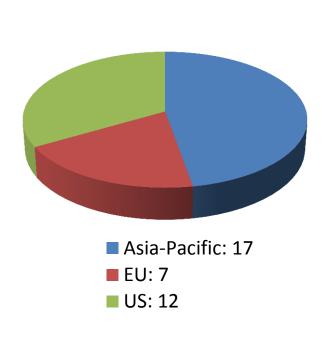




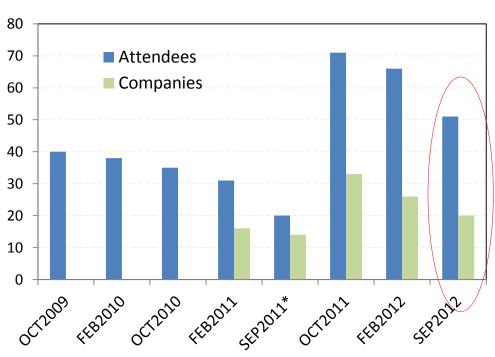
# Mask TWG Participations 2009 - 2012



## A total of 51 attended Sunday TWG (9/30), representing 20 companies or organizations



Participating companies by region (2009-2012)



\*Special TWG held at BACUS

Attendance trend: total attendees representing # of companies

#### **Next IEUVI Mask TWG**



- Schedule: In conjunction with SPIE Lithography 2013, San Jose, CA
- We are listening to suggestions on topics and priorities.
- Other inputs are welcome, as well, such as meeting formats.
- Contact / Organizing Committee:

Long He – SEMATECH / Intel (long.he @sematech.org)

John Zimmerman – ASML

Ota Kazuya – Nikon

Markus Bender – AMTC

George Huang – UMC

09/30/2012



### **Thank You!**

09/30/2012 4